

**FIRST
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

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2

Complete if Known:

Application Number	10709,622
Filing Date	May 18, 2004
First Named Inventor	Hiroshi Nogami
Examiner Name	JEFFRIE ROBERT LUND
Attorney Docket Number	001425-126

MAR 12 2005

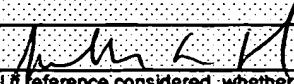
U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
1W	5,449,410		Chang et al.	09-12-1995
1W	4,792,378		Rose et al.	12-20-1998
1W	5,336,326		Karner et al.	08-09-1994
1W	5,525,159		Hama et al.	06-11-1996
1W	5,556,474		Otani et al.	09-17-1996
1W	5,942,075		Nagahata et al.	08-24-1999
1W	6,026,764		Hwang	02-22-2000
1W	6,074,518		Imafuku et al.	06-13-2000
1W	6,245,396		Negami	06-12-2001
1W	5,433,786		Hu et al.	07-18-1995
1W	5,472,565		Mundt et al.	12-05-1995
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1W	5,766,364		Ishida et al.	06-16-1998
1W	6,086,677		Umotoy et al.	07-11-2000
1W	6,203,620		Moslehi, Mehrdad M.	06-12-2001
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1W	6,534,007		Blonigan et al.	03-2003
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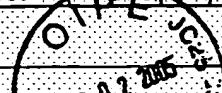
Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	STATUS						
					Translation	Partial Translation	Eng. Lang. Summary	Search Report	IPER	Abstract	Cited in Spec
1W	7-201749		Japan	08-04-1995							
1W	2837087		Japan	10-09-1998							
1W	6-260434		Japan	09-16-1994							X
1W	5-21393		Japan	01-29-1993							X

X C-10-015 892 v 10/1/04

Examiner Signature		Date Considered	5/21/05
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.
VA 696207.1

FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>(use as many sheets as necessary)</small>		Complete if Known	
		Application Number	10/709,622
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Examiner Name	JEFFRIE ROBERT LUND		
Sheet <u>1</u> of <u>2</u>	Attorney Docket Number	001425-126	

**NON-PATENT LITERATURE DOCUMENTS**

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, etc., serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<u>MR</u>	Shingo TADOMURA et al., "ANISOTROPIC ETCHING USING DEPOSITION OF SULFUR", Sony Corporation, Semiconductor World, January 1993, pp. 1-11, and translation
<u>MR</u>	Ken FUJITA et al., "X-RAY PHOTOELECTRON SPECTROSCOPIC STUDIES ON PYROLYSIS OF PLASMA-POLYMERIZED FLUOROCARBON FILMS ON Si", Jpn. J. Appl. Phys. volume 34 (1995), pp. 304-306, Part 1, NO. 1, January 1995
<u>MR</u>	Robert C. REID et al., "THE PROPERTIES OF GASES AND LIQUIDS", McGraw-Hill, Inc., Appendix B, Index
<u>MR</u>	R. Byron BIRD et al., "TRANSPORT PHENOMENA", Jon Wiley & Sons, pp. 508-509 and 512-513
<u>MR</u>	Riccardo d'AGOSTINO et al., "PLASMA ETCHING OF Si and SiO ₂ in SF ₆ -O ₂ MIXTURES", J. Appl. Phys. 52(1), January 1981, pp. 162-167
<u>MR</u>	Robert C. REID et al. "Lennard-Jones Potentials as Determined from Viscosity Data (Appendix B)", <i>The Properties of Gases and Liquids</i> , McGraw-Hill, Inc., Copyright 1987, p.734, Index
<u>MR</u>	R. Byron BIRD et al. "Diffusivity and the Mechanisms of Mass Transport; Theory of Ordinary Diffusion in Gases at Low Density", <i>Transport Phenomena</i> , John Wiley & Sons, Inc., Copyright 1960, p. 508-513
<u>MR</u>	A new technique for diagnostics of a radio-frequency parallel-plate remote plasma; N. Sano et al.; Appl. Phys. Lett 65 (2), 11 July 1994 pages 162-164.
<u>MR</u>	Infrared spectroscopic study of SiO _x films produced by plasma enhanced chemical vapor deposition; J. Vac. Sci. Technol. A4(3), May/June 1986; pages 689-694.
<u>MR</u>	Improvement of structural and electrical properties in low-temperature gate oxides for poly-Si TFTs by controlling O ₂ /SiH ₄ ratios; AM-LCD 1997; pages 87-90.
<u>MR</u>	"Flow of Atoms and Molecules—Rarefied Gas Dynamics and its Applications", section 2.6.4, The Japan Society of Mechanical Engineers, 1996, Kyoritsu Shuppan Co., Ltd.

Examiner Signature	<u>M. R. L.</u>	Date Considered	<u>5/4/05</u>
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EXAMINER: Initial reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.
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